

Substitute for PTO Form 100

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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Sheet 1 of 2

Complete if Known

Application Number	10/581,622
Date Filed:	June 5, 2006
First Named Inventor	David FORREST
Group Art Unit	1774
Examiner Name	
Attorney Docket Number	52993/326894

U.S. PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number - Kind Code ² (if known)			
/LF/		US-4,997,678	03/05/1991	Taylor, et al.	
/LF/		US-5,098,631	03/24/1992	Pyzik, et al.	
/LF/		US-5,604,151	02/18/1997	Goela, et al.	
/LF/		US-5,612,132	03/18/1997	Goela, et al.	
/LF/		US-6,042,758	03/28/2000	Goela	
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/LF/		US-2005/0123713 A1	06-09-2005	Forrest	

FOREIGN PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	Foreign Patent Document	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T ⁶
		Country Code ³ - Number ⁴ - Kind Code ⁵ (if known)				
/LF/		E P 1 127955 A1	08-29-2001	Shipley Company LLC		
/LF/		EP 0 955 278 A2	11-10-1999	CVD Incorporated		
/LF/		EP 0 588 479 A1	03-23-1994	CVD Incorporated		
/LF/		WO 99/41773	08-19-1999	Applied Materials, Inc.		

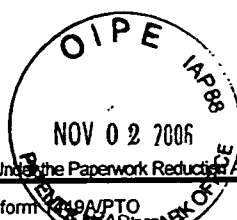
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Considered

07/31/2008

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Sheet 2 of 2	Attorney Docket Number	52993/326894	

OTHER PRIOR ART -- NON PATENT LITERATURE DOCUMENTS			
Examiner Initials *	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
/LF/		Collins, et al., 'Investigation of CVD β -SiC Surfaces Produced via a 'Novel' Surface Replication Process,' <i>Mat. Res. Soc. Symp. Proc.</i> , 168:193-198 (1990)	
/LF/		Collins, et al., 'Grain size dependence of the thermal conductivity of polycrystalline chemical vapor deposited β -SiC at low temperature,' <i>J. Appl. Phys.</i> , 68(12):6510-6512 (1990)	
/LF/		Goela and Taylor, 'Chemical Vapor Deposition for Silicon Cladding on Advanced Ceramics,' <i>J. Am. Ceram. Soc.</i> , 72(9):1747-1750 (1989)	
/LF/		Kim and Zangvil, 'Microstructure Comparison of Transparent and Opaque CVD SiC,' <i>J. Am. Ceram. Soc.</i> , 78(6):1571-1579 (1995)	
/LF/		Qadri, et al., 'Characteristics of Plasma Processed SiC Nanocrystallites and Nanorods,' <i>Applied Physics Letters, American Institute of Physics</i> , 83(3):548-550 (July 21, 2003)	

Examiner Signature	/Lawrence Ferguson/	Date Considered	07/31/2008
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